



PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Paul B. Mirkarimi et al.

Docket No. : CIL-10972

Serial No. : 10/086,614

Art Unit : 1762

Filed : March 1, 2002

Examiner : W. Markham

For : Ion-Assisted Deposition Techniques For  
The Planarization Of Topological Defects

AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed February 16, 2005, please amend the  
above-referenced application as follows: